

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE										ATTY. DOCKET NO. ONX-110		SERIAL NO. 09/724,948		
<b>LIST OF PRIOR ART CITED BY APPLICANT</b> (Use several sheets if necessary)										APPLICANT Behrang Behin et al.				
										FILING DATE 11/28/2000		GROUP 2873		
<b>U.S. PATENT DOCUMENTS</b>														
EXAMINER TRADEMARK OFFICE AUG 22 2001		DOCUMENT NUMBER							DATE	NAME	CLASS	SUB-CLASS	FILING DATE IF APPROPRIATE	
	Z. L.	A	5	7	1	7	6	3	1	2/10/96	Carley et al.	365	174	6/25/95
	↑	B	5	9	1	4	5	0	7	6/22/99	Polla et al.	257	254	10/30/96
		C	5	9	7	1	3	5	5	1026/99	Biegelsen et al.	251	129.06	11/27/96
		D	4	5	8	0	8	7	3	4/8/86	Levinson	350	96.20	12/30/83
		E	5	6	3	8	9	4	6	6/17/97	Zavracky	200	181	1/11/96
		F	5	6	4	6	4	6	4	7/8/97	Sickafus	310	40	9/20/93
		G	5	0	4	3	0	4	3	8/27/91	Howe et al.	156	645	6/22/90
		H	5	8	8	1	5	9	8	3/16/99	Sapuppo et al.	74	5.6 E	6/27/97
		I	5	9	6	3	7	8	8	10/5/99	Barron et al.	438	48	11/19/97
		J	5	6	4	8	6	1	8	7/15/97	Neukermans et al.	73	862.08	1/31/96
		K	6	0	2	5	9	5	1	2/15/00	Swart et al.	359	245	9/27/96
	↓	L	5	9	9	8	9	0	6	12/7/99	Jerman et al.	310	309	8/17/98
Z. L.	M	5	9	6	9	8	4	8	10/19/99	Lee et al.	359	298	7/3/97	
<b>FOREIGN PATENT DOCUMENTS</b>														
		DOCUMENT NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
													YES NO	
Z. L.		0	0	5	7	2	3	3	9/28/200	WIPO			X	
<b>OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)</b>														
	N													
	O	H. Toshioshi et al. "Electrostatic Micro Torsion Mirrors for an Optical Switch Matrix" Journal of Microelectromechanical Systems, vol. 5 No. 4, 231-7 Dec. 1996												
	P	L.Y. Lin et al. "Free-Space Micromachined Optical Switches with Sub-Millisecond Switching Time for Large-Scale Optical Cross Connects" OFC '98 and IEEE Photonics Technol. Lett. , April, 1998												
EXAMINER <i>Z. Ritz</i>										DATE CONSIDERED <i>07/03/2002</i>				
* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.														

## LIST OF PRIOR ART CITED BY APPLICANT

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Behrang Behin et al.FILING DATE  
11/28/2000GROUP  
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## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE
<i>F. K.</i>	A	5 8 6 7 3 0 2	2/2/1999	Fleming	359	291	8/7/1997
	B						
	C						
	D						

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
							YES NO
<i>F. K.</i>	E	0 6 8 3 4 1 4	11/22/1995	Europe	G02B	26/08	

## OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

<i>F. K.</i>	F	E. K. Chan et al, "Characterization of Contact Electromechanics Through Capacitance-Voltage Measurements and Simulations" Journal of Microelectromechanical Systems, Vol. 8, No. 2, June 1999
<i>↑</i>	G	E. K. Chan et al, "Electrostatic Micromechanical Actuator with Extended Range of Travel" Journal of Microelectromechanical Systems December 2000
<i>↓</i>	H	P. Cheung et al. "Design, Fabrication, Position Sensing, and Control of an Electrostatically-driven Polysilicon Microactuator, IEEE Transactions on Magnetics, Vol 32, No. 1, January 1996
<i>F. K.</i>	I	A. Selvakumar, "A High-Sensitivity Z-Axis Capacitive Silicon Microaccelerometer with a Torsional Suspension", Journal of Microelectromechanical Systems Vol. 7, No. 2, June 1998.

EXAMINER

DATE CONSIDERED

*F. K. R. L.**07/03/2002*

\* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.